

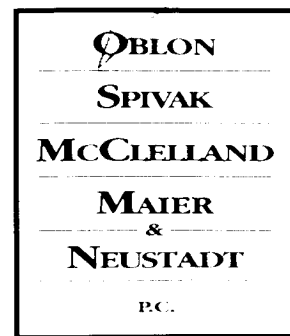
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TC 1700

Docket No.: 202450US0

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231



ATTORNEYS AT LAW

RE: Application Serial No.: 09/770,289
Applicants: Atsushi SHIOTA, et al.
Filing Date: January 29, 2001
For: PROCESS FOR PRODUCING SILICA-BASED FILM,
SILICA-BASED FILM, INSULATING FILM, AND
SEMICONDUCTOR DEVICE
Group Art Unit: 1712
Examiner: M. FEELY

SIR:

Attached hereto for filing are the following papers:

**Information Disclosure Statement Under 37 C.F.R. §1.97
Form PTO-1449**

Cited References (2) with English-language Abstract and Comments (5 pp.)

Our check in the amount of **\$180.00** is attached covering any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R. 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. 15-0030. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Atsushi SHIOTA, et al.

SERIAL NO: 09 770,289

GAU: 1712

FILED: January 29, 2001

EXAMINER: M. FEELY

FOR: PROCESS FOR PRODUCING SILICA-BASED FILM, SILICA-BASED FILM INSULATING FILM AND SEMICONDUCTOR DEVICE

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

Applicant(s) wish to disclose the following information.

REFERENCES

- ☒ The applicant(s) wish to make of record the references listed on the attached form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.
- ☒ A check is attached in the amount required under 37 CFR §1.17(p).

RELATED CASES

- ☐ Attached is a list of applicant's pending application(s) or issued patent(s) which may be related to the present application. A copy of the patent(s), together with a copy of the claims and drawings of the pending application(s) is attached along with PTO 1449.
- ☐ A check is attached in the amount required under 37 CFR §1.17(p).

CERTIFICATION

- ☐ Each item of information contained in this information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- ☒ No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

DEPOSIT ACCOUNT

- ☒ Please charge any additional fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McFILL AND,
MAIER & NEUSTADT, P.C.


Norman E. Oblon

Registration No. 24,618



22850

OSMM&N File No. 202450US0

Dept.: CHEMICAL

By: NFO/CPU/wmb

Serial No. 09/770,289

In the matter of the Application of: Atsushi SHIOTA, et al.

For: PROCESS FOR PRODUCING SILICA-BASED FILM, SILICA-BASED FILM, INSULATING FILM, AND SEMICONDUCTOR DEVICE

Due Date: N/A

The following has been received in the U.S. Patent Office on the date stamped hereon:

■ Check for \$180.00

■ Dep. Acct. Order Form

■ PTO Cover Letter

■ Information Disclosure Statement

■ PTO-1449

■ Cited References (2) w/English Abstract (1) and Comments (5 pp.)



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